Amendments to the Claims:

This listing of claims will replace all prior versions and listing of claims in the application:

Listing of Claims:

1. (Withdrawn) An apparatus for control of a fluid flow, comprising:
measuring means for measuring a pump performance parameter; and
controller means for adjusting a fluid flow in response to the pump performance parameter.

2. (Withdrawn) The apparatus of claim 1 wherein the measuring means comprises at least one sensor for measuring at least one of a pump speed, voltage, electric current, and electric power.

3. (Withdrawn) The apparatus of claim 1 wherein the measuring means comprises at least one of a voltage sensor, an electric current sensor, an electric power sensor, and a multi-component sensor.

4. (Withdrawn) The apparatus of claim 1 wherein the controller means comprises a process control computer for adjusting operation of at least one of a flow-control means and a pump.

5. (Withdrawn) The apparatus of claim 4 wherein the flow-control means comprises at least one of a valve, a pneumatic actuator, an electric actuator, a hydraulic actuator, and a micro-electric actuator.

6. (Withdrawn) The apparatus of claim 4 wherein the pump comprises a centrifugal pump.

7. (Withdrawn) An apparatus for control of a fluid flow, comprising:
measuring means for measuring a pump performance parameter;
means for comparing a measured pump performance parameter to a predetermined target pump performance parameter; and
controller means for adjusting a fluid flow in response to a difference in the

measured pump performance parameter and the predetermined target pump performance parameter.

8. (Withdrawn) The apparatus of claim 7 wherein the measuring means comprises at least one sensor for measuring at least one of a pump speed, voltage, electric current, and electric power.

9. (Withdrawn) The apparatus of claim 7 wherein the measuring means comprises at least one of a voltage sensor, an electric current sensor, an electric power sensor, and a multi-component sensor.

10. (Withdrawn) The apparatus of claim 7 wherein the controller means comprises a process control computer for adjusting operation of at least one of a flow-control means and a pump.

11. (Withdrawn) The apparatus of claim 10 wherein the flow-control means comprises at least one of a valve, a pneumatic actuator, an electric actuator, a hydraulic actuator, and a micro-electric actuator.

12. (Withdrawn) The apparatus of claim 10 wherein the flow-control means comprises means for adjusting a system element to change the resistance to flow.

13. (Withdrawn) The apparatus of claim 10 wherein the pump comprises a centrifugal pump.

14. (Withdrawn) The apparatus of claim 7 further comprising means for delivering the fluid flow to means for performing a supercritical process.

15. (Withdrawn) An apparatus for control of a fluid flow, comprising:

a pump;

a sensor for measuring a pump performance parameter; and

a controller for adjusting operation of the pump to control a fluid flow in response to the pump performance parameter.

16. (Withdrawn) The apparatus of claim 15 wherein the pump performance parameter comprises at least one of a pump speed, voltage, electric current, and electric power.

17. (Amended) A system for supercritical processing of an object, comprising:

a. means for performing a supercritical process;

b. means for measuring a pump performance parameter; and

c. means for adjusting operation of a pump to control a fluid flow in response to the pump performance parameter.

18. (Amended) The system of claim ~~19~~ 17 wherein the object is a semiconductor wafer for forming integrated circuits.

19. (Amended) The system of claim ~~19~~ 17 wherein the means for performing a supercritical process comprises a processing chamber and means for circulating at least one of a gaseous, liquid, supercritical and near-supercritical fluid within the processing chamber.

20. (Amended) The system of claim ~~21~~ 19 wherein the means for circulating is a means for circulating a ~~the~~ fluid comprising~~es~~ carbon dioxide.

21. (Amended) The system of claim ~~22~~ 20 wherein at least one of solvents, co-solvents and surfactants are contained in the carbon dioxide.

22. (Amended) The system of claim ~~19~~ 17 wherein the pump performance parameter comprises at least one of a pump speed, voltage, electric current, and electric power.

23. (Amended) The system of claim ~~19~~ 17 further comprising means for delivering the fluid flow to the means for performing a supercritical process.

24. (Withdrawn) A method of control of a fluid flow, comprising the steps of:

a. measuring a pump performance parameter; and

b. adjusting a fluid flow in response to the pump performance parameter.

25. (Withdrawn) The method of claim 26 wherein the pump operational parameter comprises at least one of a pump speed, voltage, electric current, and electric power.

26. (Withdrawn) A method of eliminating flow meter contamination in semiconductor wafer processing with a fluid, comprising the steps of:

a. measuring a pump operational parameter; and

b. adjusting operation of a pump to control a fluid flow in response to the pump operational parameter.

27. (Withdrawn) A method of control of a fluid flow, comprising the steps of:

measuring a pump performance parameter;

comparing a measured pump performance parameter to a predetermined target pump performance parameter; and

adjusting a fluid flow in response to a difference in the measured pump performance parameter and the predetermined target pump performance parameter.

28. (Original) A method of control of a fluid flow in a supercritical processing system, comprising the steps of:

a. defining a system curve including a point of operation;

b. using the system curve to define at least one of a predetermined pump speed, voltage, electric current, and electric power;

c. measuring performance of a pump to obtain at least one of a measured pump speed, voltage, electric current, and electric power;

d. comparing the at least one of a measured pump speed, voltage, electric current, and electric power to the at least one of a predetermined pump speed, voltage, electric current, and electric power;

e. adjusting operation of a pump to control a fluid flow in response to a difference in the at least one of a measured pump speed, voltage, electric current, and electric power and the at least one of a predetermined pump speed, voltage, electric current, and electric power.